Artificial intelligence (AI) gives computers the ability to see what’s happening in the world around them. Recent developments have led to the widespread use of deep learning (DL) based on image sensors. DL has become a highly successful method employed in imaging and computer vision. Although the existing technology has matured, its performance is still affected by various environmental conditions, and recent methods have attempted to fuse DL techniques with conventional methods to guarantee higher accuracy. The goal of this Special Issue (SI) is to highlight state-of-the-art works that deal with the use of DL for computer vision (CV). Papers on both theoretical studies and practical applications are welcomed. Submitted papers should present original, unpublished work relevant to one of the topics of the SI. All submitted papers will be evaluated on the basis of relevance, the significance of the contribution, technical quality, scholarship, and the quality of presentation by at least two independent reviewers.

**Scope:** (including but not limited to)
1. DL using image sensors in understanding and recognition, etc.
2. DL using image sensors in biometrics and spoof detection, etc.
3. DL using image sensors in object detection and tracking, etc.
4. Object recognition and scene understanding using CV & language.

**Guest Editor:** Prof. Chih-Hsien Hsia  
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**Important Dates:**
Submission deadline: January 15, 2020  
First round decision: March 30, 2020  
First round revision submission: April 30, 2020  
Second round decision: June 15, 2020  
Second round revision submission: July 30, 2020  
Final decision: September 01, 2020  
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If you have any questions, please feel free to contact the editorial staff at the address below.

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